INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)

Docket Number (Optional) TW1-8520	Application Number NEW 10/717, 316
Applicant(s) Allan Rosencwaig et al.	
Filing Date HEREWITH	Group Art Unit Unknown 2877

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
an	*AA	3,887,392	06/03/1975	Tang	134	1	11/23/1973
Tay _	*AB	5,261,965	11/16/1993	Moslehi	134	1	08/28/1992
(UZ)	*AC	5,306,671	04/26/1994	Ogawa et al.	437	225	06/21/1991
04/	*AD	5,316,970	05/31/1994	Batchelder et al.	250	423P	06/05/1992
CAN	*AE	5,439,596	08/08/1995	Ohmi et al.	210	748	07/02/1992
OR	*AF	5,449,411	09/12/1995	Fukuda et al.	118 .	723 MP	10/19/1993
Qu	*AG	5,798,837	08/25/1998	Aspnes et al.	356	369	07/11/1997
Que .	*AH	6,325,078	12/04/2001	Kamieniecki	134	1.3	01/07/1998

FOREIGN PATENT DOCUMENTS

	DOCUMENT		1		TRANSLATION		
REF	Number	DATE	COUNTRY	CLASS	- SUBCLASS	YES	No
*AI	WO 5/00681	01/05/1995	PCT	C23G	1/00		
*AJ	1043 VOOT	11/08/1996	Japan	B08B	3/12		
*AK	WO 98/05066	02/05/1608	NOIDEREA	H01L	21/66		
 *AL	WO 99/35677	07/15/1999	PCT	H01L	21/306		
*AM	4-357836	12/10/1999	Japan ·	HOIL	21/304		

OTHER DOCUMENTS
(Including Author, Title, Date, Pertinent Pages, Etc.)

1/2=	*AN	K. Imen et al., "Laser-assisted micron scale 205.	particle removal, " App. Phys. Lett., Vol. 58, No. 2, 14 January 1991, pp. 203-
70 0			
		519 Cren	
Examiner	W/\	n wh	Date Considered 23 July 2004
		citation considered, whether or not citation and not considered. Include copy of this for	is in conformance with MPEP Section 609; Draw line through citation if m with next communication to applicant.